



IFW AFAS  
Patent  
CIT.PAU.01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  
Scherer et.al.

Examiner: R.McDonald  
Group Art Unit: 1753

Serial No.: 10/068,283

Filed: Feb. 5, 2002

For: Dry Etching and Mirror  
Deposition Processes for Silicone  
Elastomer

AMENDMENT AFTER FINAL

Hon. Commissioner of Patents and Trademarks  
Washington DC 20231

Sir:

In reply to the Office Sept. 10, 2004, please consider the following  
remarks and enter the following amendments. Enclosed is a check for  
additional claims added by this amendment.

**Amendments to the Claims** are reflected in the listing of claims which  
begins on page 2 this paper.

**Remarks** begin on page 8 of this paper.

09/28/2004 FHETEKI1 00000013 10068283

01 FC:2201  
02 FC:2202

43.00 OP  
27.00 OP

DO NOT  
ENTER 10/16/04